EPS 2018 Programme

Monday, July 2, 2018

LTDP - Mánes Bar (4:30 PM - 6:30 PM)

-Conveners: U. Cvelbar

time	[id] title	presenter
4:30 PM	[5321] I1.301 Challenges for the development of plasma-based atomic layer processing - numerical and experimental analyses of plasma-exposed surface reactions at the atomic level	HAMAGUCHI, Satoshi
5:00 PM	[5322] I1.302 Plasma-surface interaction studies: Development and application of advanced laser-based diagnostics	HELDEN, Jean-Pierre Hubertus van
5:30 PM	[5323] I1.303 Sensitive measurement of sheath electric field by Stark spectroscopy using the Balmer-alpha line of atomic hydrogen	SASAKI, Koichi
6:00 PM	[5324] I1.304 Application of the PI-VM (Plasma Information based Virtual Metrology) for management of the plasma processes in OLED display manufacturing	PARK, Seolhye